

ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of Invention	APPARATUS AND METHOD FOR MANIPULATING SAMPLE TEMPERATURE FOR FOCUSED ION BEAM PROCESSING						
Application Number :							
Confirmation Number:							
First Named Applicant:	Chad Rue						
Attorney Docket Number:	FIS920040175US1						
Art Unit:							
Examiner:							
Search string:	(6365905 or 20040060904 or 20040112857 or 20040129879 or 20040132287).pn						
US Patent Documents							
Note: Applicant is not required to submit a paper copy of cited US Patent Documents							
init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	6365905	2002-04-02	KOYAMA, ET AL.			
US Published Applications							
Note: Applicant is not required to submit a paper copy of cited US Published Applications							
init	Cite.No.	Pub. No.	Date	Applicant	Kind	Class	Subclass
	1	20040060904	2004-04-01	HERSCHBEIN, ET AL.			
	2	20040112857	2004-06-17	HERSCHBEIN, ET AL.			
	3	20040129879	2004-07-08	FURIKI, ET AL.			
	4	20040132287	2004-07-08	FISCHER, ET AL.			

Signature

Examiner Name	Date